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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant:

Richard A. Blanchard

Assignee:

Siliconix incorporated

Title:

"PLANAR VERTICAL CHANNEL DMOS STRUCTURE"

Serial No.:

06/843,454

Filing Date: 03/24/86

Examiner:

T. Thomas

Art Unit: 114

Attorney Docket No.: M-300 US

Santa Clara, California November 23, 1987

COMMISSIONER OF PATENTS & TRADEMARKS Washington, D. C. 20231

AMENDMENT

Sir:

In response to the Office Action of June 22, 1987, please amend the application as follows:

IN THE CLAIMS

Please amend the claims as follows:

(Amended). A method of making a semiconductor device comprising the following steps:

forming a first region of a semiconductor material having a first conductivity type;

forming a second region of a semiconductor material having a second conductivity type above and in contact with said first region, said second region having a top surface;

 $\int_{\{}^{}$ forming a third region of said first conductivity type in a first portion of said second region, said third region extending to a first portion of said top surface;

forming a first [rectangular] groove in said first portion of said top surface, said first [rectangular]

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